

L Number	Hits	Search Text	DB	Time stamp
1	0	"10655850"	USPAT; US-PGPUB	2004/10/31 11:33
2	0	10/655850	USPAT; US-PGPUB	2004/10/31 11:34
-	444	702/82-84.ccls.	USPAT; US-PGPUB	2004/10/31 10:47
-	469	700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 09:29
-	833	702/82-84.ccls. or 700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 09:29
-	926	700/121.ccls. not 700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 10:13
-	116	(700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same yield)	USPAT; US-PGPUB	2004/10/30 10:21
-	327	(700/121.ccls. not 700/109,110.ccls.) and yield	USPAT; US-PGPUB	2004/10/30 10:21
-	211	((700/121.ccls. not 700/109,110.ccls.) and yield) not ((700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same yield))	USPAT; US-PGPUB	2004/10/30 10:25
-	301	determin\$3 with yield with loss	USPAT; US-PGPUB	2004/10/30 10:31
-	35	determin\$3 with yield with loss same (semiconductor or wafer)	USPAT; US-PGPUB	2004/10/30 10:31
-	5	"6367040"	USPAT; US-PGPUB	2004/10/30 10:51
-	16	("4801869" "5355212" "5438527" "5598341" "5754432" "5761064" "5777901" "5787190" "5822218" "5828778" "5940300" "5943437" "6016562" "6017771" "6061814" "6169960").PN.	USPAT	2004/10/31 09:00
-	4	("3751647" "5544256" "5777901" "6265232").PN.	USPAT	2004/10/31 09:08
-	192	kill adj2 ratio	USPAT; US-PGPUB	2004/10/31 09:30
-	0	kill adj2 ratio same calibrat\$3	USPAT; US-PGPUB	2004/10/31 09:30
-	13	kill adj2 ratio and calibrat\$3	USPAT; US-PGPUB	2004/10/31 09:32
-	7	kill adj2 ratio same weight\$3	USPAT; US-PGPUB	2004/10/31 10:33
-	0	yield with impact with calibrat\$3 with factor	USPAT; US-PGPUB	2004/10/31 11:33
-	14	yield same impact same calibrat\$3 same factor	USPAT; US-PGPUB	2004/10/31 10:34
-	142	kill adj2 ratio and weight\$3	USPAT; US-PGPUB	2004/10/31 10:42
-	3	yield adj2 loss and calibration adj2 factor	USPAT; US-PGPUB	2004/10/31 10:57
-	139	defect with excursion	USPAT; US-PGPUB	2004/10/31 10:47
-	0	defect with excursion with limit	USPAT; US-PGPUB	2004/10/31 10:47
-	3	defect with excursion same calibrat\$3	USPAT; US-PGPUB	2004/10/31 10:51
-	18	defect with calibrat\$3 with factor	USPAT; US-PGPUB	2004/10/31 10:52
-	359	yield adj2 loss and calibrat\$3	USPAT; US-PGPUB	2004/10/31 10:57



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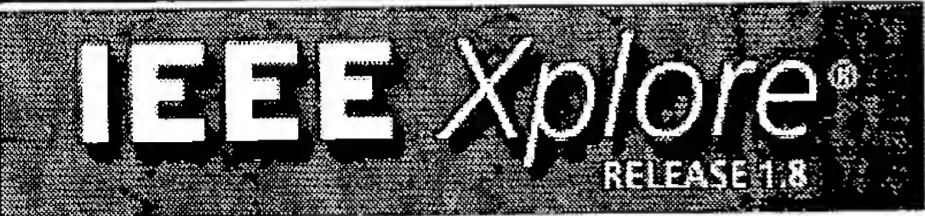
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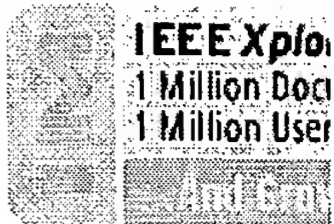
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1 **SmartBit™: bitmap to defect correlation software for yield improvement**
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Advanced Semiconductor Manufacturing Conference and Workshop, 2000
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Patterson, O.D.; Hansen, M.H.;

Semiconductor Manufacturing, IEEE Transactions on , Volume: 15 , Issue: 4 , Nov. 2002

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2 The impact of tolerance on kill ratio estimation for memory

Patterson, O.D.; Hansen, M.H.;

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3 Critical area based yield prediction using in-line defect classification information [DRAMs]

Segal, J.; Sagatelian, A.; Hodgkins, B.; Ben Chu; Singh, T.; Berman, H.;

Advanced Semiconductor Manufacturing Conference and Workshop, 2000
IEEE/SEMI , 12-14 Sept. 2000

Pages:83 - 88

[\[Abstract\]](#) [\[PDF Full-Text \(508 KB\)\]](#) **IEEE CNF**

4 Evaluation of the yield impact of epitaxial defects on advanced semiconductor technologies

Williams, R.; Jacques, R.; Akbulut, M.; Wayne Chen;

Advanced Semiconductor Manufacturing Conference and Workshop, 2000
IEEE/SEMI , 12-14 Sept. 2000

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5 SmartBit™: bitmap to defect correlation software for yield improvement

Merino, M.A.; Cruceta, S.; Garcia, A.; Recio, M.;

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Pages:194 - 198

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6 Key considerations in the development of defect sampling methodologies

McIntyre, M.; Nurani, R.K.; Akella, R.;

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC

96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996

Pages:81 - 85

[\[Abstract\]](#) [\[PDF Full-Text \(484 KB\)\]](#) IEEE CNF

7 Limitations to estimating yield based on in-line defect measurements

Riley, S.L.;

Defect and Fault Tolerance in VLSI Systems, 1999. DFT '99. International

Symposium on , 1-3 Nov. 1999

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